

START TO END SIMULATIONS AND MACHINE SENSITIVITY STUDY FOR THE ELI-NP γ-SOURCE



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Start to end simulations and machine sensitivity study for the ELI-NP y-source

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<u>Abstract</u>

The ELI-NP Gamma Beam System is an advanced gamma ray source up to 20 MeV based on Compton back-scattering effect, presently under construction in Magurele-Bucharest (RO). Here the head-on collision is foreseen between an intense high power laser beam and a high brightness electron beam with a maximum kinetic energy of 740 MeV. Start to end simulations of the ELI-NP Gamma Source are here presented regarding the machine sensitivity to the possible jitters and misalignments. The effects on the beam quality are illustrated providing the basis for the alignment procedure and jitters tolerances.

The ELI-NP γ-source

Peculiarities of the γ -source are:

- 1. Energy tunability of the γ -source in the range [0.2 20.0] MeV
- 2. Mono-chromaticity of the γ -source with a BW (rms) $\leq 0.5\%$



1. Energy Tunability of Electron Beam

2. $0.04\% \leq$ Energy Spread of Electron Beam (%) $\leq 0.1\%$



The ELI-NP γ-source



envelope and rms bunch length at the injector exit

Courtesy of A. Bacci - INFN-MI







The ELI-NP γ-source





Beams	Parameters	@IP
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Electron Beam Q = 25 - 400 pC			
Energy	80 - 740	MeV	
Energy spread	0.04 - 0.1	%	
Bunch length	100 - 400	μm	
ε _{nx.v}	0.2 – 0.6	mm mrad	
Focal Spot Size	> 15	μm	
Laser Beam λ = 515 nm			
Energy	0.2 - 0.4	J	
Focal Spot Size	> 28	μm	

GBS - Beam Specifications			
Energy	0.2 – 20.0	MeV	
Flux within	≤ 2.6•10 ⁵	N _{ph} /pulse	
Peak brilliance	10 ²⁰ - 10 ²³	N _{ph} /s∙mm²∙ mrad²∙0.1%	
BW (rms)	≤ 0.5	%	
Source Size	10 - 30	μm	

Technical Design Report E-Gammas proposal for the ELI-NP Gamma beam System With 79 tables and 252 figures

O. Adriani, S. Albergo, D. Alesini, M. Anania, D. Angal-Kalinin, P. Antici, A. Bacci, R. Bedogni, M. Bellaveglia, C. Biscari, N. Bliss, R. Boni, M. Boscolo, F. Broggi, P. Cardarelli, K. Cassou, M. Castellano, L. Catani, I. Chaikovska, E. Chiadroni, R. Chiche, A. Cianchi, J. Clarke, A. Clozza, M. Coppola, A. Courjaud, C. Curatolo, O. Dadoun, N. Delerue, C. De Martinis, G. Di Domenico, E. Di Pasquale, G. Di Pirro, A. Drago, F. Druon, K. Dupraz, F. Egal, A. Esposito, F. Falcoz, B. Fell, M. Ferrario, L. Ficcadenti, P. Fichot, A. Gallo, M. Gambaccini, G. Gatti, P. Georges, A. Ghigo, A. Goulden, G. Graziani, D. Guibout, O. Guilbaud, M. Hanna, J. Herbert, T. Hovsepian, E. Iarocci, P. Iorio, S. Jamison, S. Kazamias, F. Labaye, L. Lancia, F. Marcellini, A. Martens, C. Maroli, B. Martlew, M. Marziani, G. Mazzitelli, P. McIntosh, M. Migliorati, A. Mostacci, A. Mueller, V. Nardone, E. Pace, L. Palumbo, A. Pelorosso, F.X. Perin, G. Passaleva, L. Pellegrino, V. Petrillo, M. Pittman, G. Riboulet, R. Ricci, C. Ronsivalle, D. Ros, A. Rossi, L. Serafini, M. Serio, F. Sgamma, R. Smith, S. Smith, V. Soskov, B. Spataro, M. Statera, A. Stecchi, A. Stella, A. Stocchi, S. Tocci, P. Tomassini, S. Tomassini, A. Tricomi, C. Vaccarezza, A. Variola, M. Veltri, S. Vescovi, F. Villa, F. Wang, E. Yildiz, F. Zomer



Machine Error Sensitivity Studies

The Method:

- > The beamline has been preliminary matched for the ideal electron beam.
- Misalignments and jitters have been introduced both in the injector and all along the linac with the aim to provide specifications for jitters and alignments of accelerating structures and magnets.
- Error matrices from injector and linac have been coupled one with each other randomly.
- Error value distributions are calculated according to the latin hypercube scheme (as reported in the TDR) by using a matrix of the latin hypercube randomly factorizes in the range [-100 : +100]% of error values.
- Data analysis has been done on 100 bunches, each composed of 30k macro particles.

Injector Error Sensitivity Studies

Specifications for cathode laser system, power supplies and solenoids

- Injector sensitivity analysis has been performed over a random sampling of 100 runs, by using the codes Giotto and Astra.
- In table the considered errors on all devices

Errors on GUN		
RF Voltage [ΔV]	0.2	%
RF Phase [Δφ]	200	fs
Errors on S-band Accelerating Sections		
RF Voltage [Δ V]	0.2	%
RF Phase [Δφ]	200	fs
Alignment on transverse plane [Δxy]	70	μm
Errors on Solenoids (GUN & TW cavities)		
Alignment on transverse plane [Δxy]	70	μm
Errors on Cathode Laser System		
Arrival time [Δt]	200	fs
Pointing Instabilities [Δ s]	20	μm
Energy Fluctuation	5	%

Courtesy of A. Bacci - INFN-MI

Specifications for power supplies and magnetic elements

- Linac sensitivity analysis has been performed over a recursive sampling of 100 runs, by using the Elegant code.
- In table the considered errors on all devices

Errors on C-band Accelerating Sections		
RF Voltage [ΔV]	0.2	%
RF Phase [Δφ]	1	Deg
Alignment on transverse plane [Δxy]	0,70,100	μm
Errors on Quadrupoles		
Geometric strength [Δk]	0.3	%
Alignment on transverse plane [Δxy]	0,70,100	μm
Rotation about incoming longitudinal axis $[\Delta \Theta]$	1	mrad
Errors on Dipoles		
Bend angle [ΔB]	0.1	%
Rotation about incoming longitudinal axis $[\Delta \Theta]$	1	mrad
Errors on Steerers		
Strenght Jitters [ΔB]	0.2	μrad
Errors on BPMs		
Noise	20	μm

Specifications for power supplies and magnetic elements

Machine sensitivity analysis suggests that the most critical parameters are the RF phase jitter on accelerating structures and misalignments on magnetic elements



Electron beam spot size at low energy IP in case of $\Delta xy=70-100\mu m$, jitters on RF system and on magnetic elements

Specifications for power supplies and magnetic elements



Specifications for power supplies and magnetic elements





Specifications for power supplies and magnetic elements



Specifications for power supplies and magnetic elements



280 MeV @IP	Without errors	With errors	
Bunch charge	250	250 ± 25	рС
Energy spread	0.075	0.079 ± 0.039	%
Bunch length	280	273.3 ± 4.6	μm
٤ _{nx.v}	0.45	0.48 ± 0.03	mm mrad
Focal Spot Size	20.0	23.9 ± 1.5	μm
ΔC_{x-y}	0	8 ± 2	μm

ELI-NP γ-Source

γ-source sensitivity analysis has been performed in order to investigate degradation of the bandwidth and flux due to misalignments and jitters in the linac.



2.85 MeV @IP	Without errors	With errors	
Electron	250	250 + 25	nC
bunch charge	250	250 ± 25	pe
Collimation	102 E	102 E	urad
Angle [O]	192.5	192.5	μιαυ
Total Flux	8.7∙10 ⁶	$(8.0 \pm 1.7) \cdot 10^{6}$	N _{ph} /pulse
Flux within	1 4 • 1 • 5	$(12 \pm 02) \cdot 105$	N /pulco
FWHM BW	1.4•10°	$(1.5 \pm 0.2)^{\bullet}10^{\circ}$	N _{ph} /puise
BW	0.50	0.55 ± 0.02	%

Courtesy of I. Drebot- INFN-MI

Conclusions

- Start to end simulations has been presented for the ELI-NP Gamma Beam System
- Machine sensitivity analysis suggests that the machine is robust to errors in the specified range
- Tolerances regarding jitters and alignments of accelerating structures and magnets has been provided

Thank you!!!